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Application Information

Title Line One:: MASK, EXPOSURE METHOD, LINE WIDTH
Title Line Two:: MEASURING METHOD, AND METHOD FOR
Title Line Three:: MANUFACTURING SEMICONDUCTOR DEVICES

Title Line Four::
Total Drawing Sheets:: 16
Docket Number:: 108057

Continuity Information

>This application is a::
Application One::
Filing Date::
Patent Number::
which is a::
>>Application Two::
Filing Date::
Patent Number::

Prior Foreign Applications

Foreign Application One:: 11-348196
Filing Date:: December 7, 1999
Country:: Japan
Priority Claimed:: yes
Foreign Application Two::
Filing Date::
Country::
Priority Claimed::
Foreign Application Three::
Filing Date::
Country::
Priority Claimed::